

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of

OSAMU NAKAMURA

U.S. Patent No. 6,129,047

Issued: October 10, 2000

U.S. Serial No.

Filed: July 3, 2003

SUSCEPTOR FOR VAPOR-PHASE
GROWTH APPARATUS

Prior Application:
USSN 10/233,546
Group Art Unit 1763
J. Lund, Examiner

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Alexandria, Virginia
July 3, 2003

Commissioner for Patents
P.O. Box 1450
Alexandria, Virginia 22313-1450

PRELIMINARY AMENDMENT

Dear Sir:

This is being filed concurrently with the
captioned reissue divisional application. Please amend the
captioned patent as follows:

IN THE CLAIMS:

Cancel claims 1 and 2 without prejudice.

Add new claims 3-6 as follows:

3. (New) A method for growing an epitaxial layer
having a lower concentration than a dopant concentration of
a wafer, the method comprising:

- positioning a wafer in relation to a susceptor, the
susceptor having a through-hole;